

N THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application of

Allan Rosencwaig et al.

Application No.: 09/629,407

Filed: August 1, 2000

For: MEASUREMENT OF THIN FILMS

AND BARRIER LAYERS ON

PATTERNED WAFERS WITH X-RAY

REFLECTOMETRY

Group Art Unit: 2876

Examiner:

SECOND SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope, addressed to: Commissioner for Patents, Washington, DC 20231 on April 18. 2002.

STALLMAN & POLLOCK ĻLP

Dated: 04/ 18 /2002 B

Georgia K. Stith

Commissioner for Patents Washington, D.C. 20231

Sir:

Applicants submit herewith patents, publications or other information [attached hereto and listed on the attached Form PTO-1449 (modified)] of which they are aware, which they believe may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

This Information Disclosure Statement:

- (a) accompanies the new patent application submitted herewith. 37 CFR § 1.97(a).
- (b) is filed within three months after the filing date of the application or within three months after the date of entry of the national stage of a PCT application as set forth in 37 CFR § 1.491.
- (c) as far as is known to the undersigned, is filed before the mailing date of a first Office Action on the merits.
- (d) is filed after the first office action and more than three months after the application's filing date or PCT national stage date of entry filing but, as far as is

(l) given for each listed item
(m) given for only non-English language listed item(s) [Required]
(n) is in the form of an English language copy of a Search Report from a foreign
patent office, issued in a counterpart application, which refers to the relevant
portions of the references [copy attached].
The Examiner is reminded that a "concise explanation of the relevance" of the submitt
may be nothing more than identification of the particular figure or paragraph of the pat

ed items " ent or publication which has some relation to the claimed invention," MPEP § 609.

While the information and references disclosed in this Information Disclosure Statement may be "material" pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 CFR § 1.56(a) exists. It is submitted that the Information Disclosure Statement is in compliance with 37 CFR § 1.98 and MPEP § 609 and the Examiner is respectfully requested to consider the listed references.

冈 The Commissioner is hereby authorized to charge our Deposit Account No. 50-1703 for any fees required in connection with the filing of this Information Disclosure Statement. A duplicate copy of this Notice is enclosed for this purpose. In particular, in the event that an Office Action has crossed in the mail with this Information Disclosure Statement, the Commissioner is authorized to charge the above-named deposit account for any fees required pursuant to CFR §§ 1.17(p) or 1.17(i)(1).

Respectfully submitted,

STALLMAN & POLLOCK LLP

Dated: April 18, 2002

Michael A. Stallman Reg. No. 29,444

Attorneys for Applicant(s)

COPY OF PAPERS ORIGINALLY FILED

INFORMATION DISCLOSU O (User everal sheets if no	Docket Number (Optional) . Application Number TWI-10820 . 09/629,407 Applicant(s) Allan Rosencwaig et al.					
APR 3 0 2002	U.S. PAT	Filing Date August 1, 2000 ENT DOCUMENTS	Group Art 2876	Group Art Unit 2876		
*EXMINER NUMBER	DATE	Name	C	LASS	SUBCLASS	FILING DATE
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FOREIGN PATENT DOCUMENTS

	[DOCUMENT					Translation	
L	REF	Number	DATE	COUNTRY	CLASS	SUBCLASS	YES	No
	CA	WO 01/71325	09/27/2001	PCT	G01N	23/00		

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

СВ	E. Lüken et al., "Growth monitoring of W/Si X-ray multilayers by X-ray reflectivity and kinetic ellipsometry," SPIE, Vol. 2253. November 1994, pp. 327-332.

Examiner **Date Considered**

Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include Copy of this form with next communication to applicant.

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